EAST - [Untitled1]

File View Edit Tools Window Help

- Drafts
- Pending
- Active
  - L1: (24) wafer with transfer with manual$2 with automatic$4
- Failed
- Saved
- Favorites
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- UDC
- Queue
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DBs: US-PGPUB,USPAT

Default operator: ADJ

wafer with transfer with manual$2 with automatic$4

☐ Plurals
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BRS form | IS&R form | Image | Text | HTML

	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Inventor	U	S	C	P	1	3	Pri
1	US 20050170307 A1	20050804	13	Heat treatment jig for semiconductor silicon substrate	432/253		Adachi, Naoshi	☑	☐	☐	☐	☐	☐	☐
2	US 20030139852 A1	20030724		Method of determining retreat permission position of carrier arm and teaching	700/258	700/245	Kataoka, Yukinori et al.	☑	☐	☐	☐	☐	☐	☐
3	US 20030021671 A1	20030130		Substrate processing apparatus, method of controlling substrate, and exposure	700/121	156/345.31; 414/939	Edo, Ryo	☑	☐	☐	☐	☐	☐	☐
4	US 20030015290 A1	20030123		Substrate processing apparatus, substrate processing method, and	156/345.27	118/712; 118/719;	Edo, Ryo	☑	☐	☐	☐	☐	☐	☐
5	US 20020021837 A1	20020221		ID recognition apparatus and ID recognition sorter system for	382/181		Suzuki, Eiko	☑	☐	☐	☐	☐	☐	☐
6	US 20020006324 A1	20020117		APPARATUS AND METHOD FOR AUTOMATICALLY TRANSFERRING WAFERS BETWEEN WAFER	414/416.12	118/500; 134/902;	SATO, MICHITO et al.	☑	☐	☐	☐	☐	☐	☐
7	US 20010021340 A1	20010913		Method for automatically transferring wafers between wafer holders in a liquid	414/404	414/416.02; 414/811;	Sato, Michito et al.	☑	☐	☐	☐	☐	☐	☐
8	US 6778879 B2	20040817		Automated material handling system and method of use	700/223	700/228	Chang; Ko-Pin et al.	☑	☐	☐	☐	☐	☐	☐
9	US 6732855 B1	20040511		Conveying element and conveyor means for conveying wafer receptacles, and method	198/782	193/35R	Lering; Michael et al.	☑	☐	☐	☐	☐	☐	☐
10	US 6698991 B1	20040302		Fabrication system with extensible equipment sets	414/217	414/939; 414/940	Bachrach; Robert Z. et al.	☑	☐	☐	☐	☐	☐	☐
11	US 6643564 B2	20031104		Method of determining retreat permission position of carrier arm and teaching	700/258	250/206.1; 369/53.19;	Kataoka; Yukinori et al.	☑	☐	☐	☐	☐	☐	☐
12	US 6457929 B2	20021001		Apparatus and method for automatically transferring wafers between wafer	414/404	118/423; 118/428;	Sato; Michito et al.	☑	☐	☐	☐	☐	☐	☐

Hts | Details | HTML

Ready

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EAST - [Untitled 1]

File View Edit Tools Window Help

- Drafts
- Pending
- Active
  - L1: (24) wafer with transfer with manual$2 with automatic$4
  - L2: (5) wafer with transfer with manual$2 with automatic$4
- Failed
- Saved
- Favorites
- Tagged (0)
- UDC
- Queue
- Trash

Search | List | Browse
DBs: EPO;JPO;IBM_TDB
Default operator: ADJ   Clear

wafer with transfer with manual$2 with automatic$4

☐ Pixels
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	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Inventor	U	S	C	P	1	3	PT
1	JP 03125453 A	19910528		SEMICONDUCTOR WAFER TRANSFER DEVICE		414/937	SAKAYA, KAZUHIRO et al.	☑	☑	☐	☐	☐	☐	☐
2	JP 61256620 A	19861114		DESCRIMINATION DEVICE FOR WAFER		257/E21.002; 438/17	YAMAMOTO, SHINICHI	☑	☑	☐	☐	☐	☐	☐
3	JP 58194348 A	19831112		AUTOMATIC CLASSIFICATION CONFIRMATION SYSTEM FOR CHIP IN WAFER		257/E21.521; 438/17	YOKOYAMA, AKIO et al.	☑	☑	☐	☐	☐	☐	☐
4	JP 58056330 A	19830404		EXPOSING DEVICE IN CONTRACTED MANNER		430/22	HAYASHI, SOICHIRO et al.	☑	☑	☐	☐	☐	☐	☐
5	WO 9910915 A1	19990304		DEVICE FOR INTERMEDIATE STORAGE OF WAFERS			BALG, CHRISTIAN et al.	☑	☑	☐	☐	☐	☐	☐

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